

SHIGA7.055APC

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Hirayama et al.
 Appl. No. : U.S. National Phase of
 PCT/JP2005/001798
 Filed : Herewith
 For : BASE MATERIAL FOR
 PATTERN-FORMING
 MATERIAL, POSITIVE RESIST
 COMPOSITION AND METHOD
 OF RESIST PATTERN
 FORMATION
 Examiner : Unassigned
 Group Art Unit : Unknown

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

August 17, 2006

(Date)

Neil S. Bartfeld, Ph.D., Reg. No. 39,901

PRELIMINARY AMENDMENT

Mail Stop PCT
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

Dear Sir:

Prior to examination of the above-referenced application, please enter the following amendments:

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 5 of this paper.